



Serial No. 10/715,058

IN THE SPECIFICATION:

Please replace paragraph number [0014] with the following rewritten paragraph:

[0014] FIGS. 3 through 8 illustrate cross-sectional views of a process of forming emitters according to the present invention;~~and~~

Please replace paragraph number [0015] with the following rewritten paragraph:

[0015] FIG. 9 illustrates the uniformity of an emitter array of the ~~present invention.~~
invention;

Please insert paragraph number [0015.1] directly below paragraph number [0015] with the following paragraph:

[0015.1] FIG. 10 illustrates the distribution of mask sizes of an embodiment of the present invention; and

Please insert paragraph number [0015.2] directly below paragraph number [0015.1] with the following paragraph:

[0015.2] FIG. 11 illustrates the distribution of emitter heights according to an embodiment of the invention.

Please replace paragraph number [0031] with the following rewritten paragraph:

[0031] Next, referring to Figure 10, a controlled distribution of mask sizes is determined. The controlled distribution of mask-sizes sizes 21 is selected so that when emitting layer 20 is etched, the controlled distribution of emitter-sizes, sizes 13, including the at least one desired emitter size throughout the panel, is formed, as shown in Figure 11. The controlled distribution of mask sizes depends in part on the number and size of etching areas (e.g., the periphery and the interior) and the number of different mask sizes to be employed.